



**DYNAMIC SOLUTIONS THE LINK TO BRIDGING CONCEPTS**



M 600  
FULLY-AUTOMATED STOCKER

**FULLY AUTOMATED FOUP CLEANING**  
**INTERNAL FOUP BUFFER**  
**MANUAL OPERATION POSSIBLE**  
**OHT / AGV**

## **M 600**

### **Fully Automated Centrifugal Force Cleaner**



# *Dynamic Micro Systems*



**東横化学株式会社**  
**TOYOKO KAGAKU CO., LTD.**

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## Performance

State of the art Cleaning

Excellent IR-drying

Short cycle time

Low CoO

# M 600

## FULLY AUTOMATED CENTRIFUGAL FORCE CLEANER



## Features

Mini-environment & ESD

Small footprint

High product flexibility

RF-tag identification

S2/S8 compliant



## Software Features

Flexible use of load ports, internal buffer and cleaner chambers. Full automatic host controlled job management and carrier tracking. Modular state of the art software / controller architecture, SEMI E95 user interface, SEMI compliant SECS / GEM Host Interface (SEMI E4, E5, E30, E37, E39, E40, E87, E94)

Special DI water spray nozzle design for better coverage

Adjustable for dirty spots



## OPTIONS

Buffer

OHT/AGV interface

Metal / Non metal separation

SEMI E84 OHT/AGV/PGV/RGV

interfaces for load ports,

SEMI E58, E116 performance

tracing

High pressure DI water rinse



## Facility Requirements

3200 x 2800 x 3000 mm (WDH)

Weight : 2500 kg

Power: 208 - 480 VAC 50/60 Hz

for more information please contact DMS direct

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